

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Stefan Peter Hau-Riege

Docket No.: IL-11154

Serial No.: 10/783,520

Group Art Unit: 2877

Filed : February 20, 2004

Examiner: S. Nguyen

For : Method For Characterizing Mask Defects Using Image Reconstruction From X-Ray Diffraction Patterns

PETITION FOR EXTENSION OF TIME UNDER 37 CFR 1,136(a)

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Dear Sir:

This is a request under the provisions of 37 CFR 1.136(a) to extend the period for filing a reply in the above identified application.

The requested extension fee for a three month extension (37 CFR 1.17(a)(3) is

\$1020. Applicant claims small entity status, and the resulting fee is <u>\$510</u>.

The Commissioner is hereby authorized to charge this fee (**\$510**) to Deposit

Account Number 501913.

If any impediments remain, please contact the undersigned at 808-875-0012.

Respectfully submitted,

01/05/2007 SFELEKE1 00000005 501913 10783520 01 FC:2253 510.00 DA

hn P. Wooldudge

John P. Wooldridge Attorney for Applicant Registration No. 38,725

Dated: December 26, 2006